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## IN THE U.S. PATENT AND TRADEMARK OFFICE

February 7, 2006

Applicant : Mikio SUGIMOTO  
For : MANUFACTURING METHOD OF METAL ION WATER,  
WATER TREATMENT METHOD USING THE MANUFACTURING  
METHOD, MANUFACTURING DEVICE OF METAL ION WATER,  
AND WATER TREATMENT APPARATUS USING THE  
MANUFACTURING DEVICE

PCT International Application No.: PCT/JP2004/011721

PCT International Filing Date: August 9, 2004

U.S. Application No.

(if known, see 37 CFR 1.5): Unknown

Atty. Docket No.: 4900.P0056US


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P.O. Box 1450  
Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the provisions of Rules 1.97(b)(1) and 1.98, enclosed herewith is a copy of the International Search Report, Form PTO-1449 and the references cited thereon. The relevance of these references is explained on the enclosed search report. Accordingly, further comment at this point in time should not be necessary.

Respectfully submitted,

  
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Encl: Copy of International Search Report  
Form PTO-1449 and one copy of each reference listed  
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## U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	Document Number - Kind Code	Publication Date MM-DD-YYYY	Name of Patentee or Applicant
	AA			
	AB			
	AC			
	AD			
	AE			
	AF			

## FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.	Country Code - Document Number - Kind Code	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Trans.
/A.P./	AG	JP 10-323671	12-08-1998	MITSUMOTO et al	Abstract
/A.P./	AH	JP 9-253627	09-30-1997	NISHIBORI et al	Abstract
/A.P./	AI	JP 2000-24675	01-25-2000	OTSUKA	Abstract
/A.P./	AJ	JP 11-192492	07-21-1999	SOENO	Abstract
/A.P./	AK	JP 62-258791	11-11-1987	JIYATSUKU	Abstract
/A.P./	AL	JP 11-156367	06-15-1999	SHINAGAWA	Abstract
/A.P./	AM	JP 59-70457	04-20-1984	SATOU et al	Abstract
/A.P./	AN	JP 6-206804	07-26-1994	MOTOMURA et al	Abstract

## NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	(Include Author, Title, Date, Pages, Etc.)
	AO	
	AP	
EXAMINER SIGNATURE		DATE CONSIDERED
/Arun Phasge/		09/08/2009

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